

Solid Sample Analysis of non-metallic elements (I,P,S) via Electrothermal Vaporisation by Optical Emission Spectroscopy with Inductively Coupled Plasma

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ETV: Principle of operation

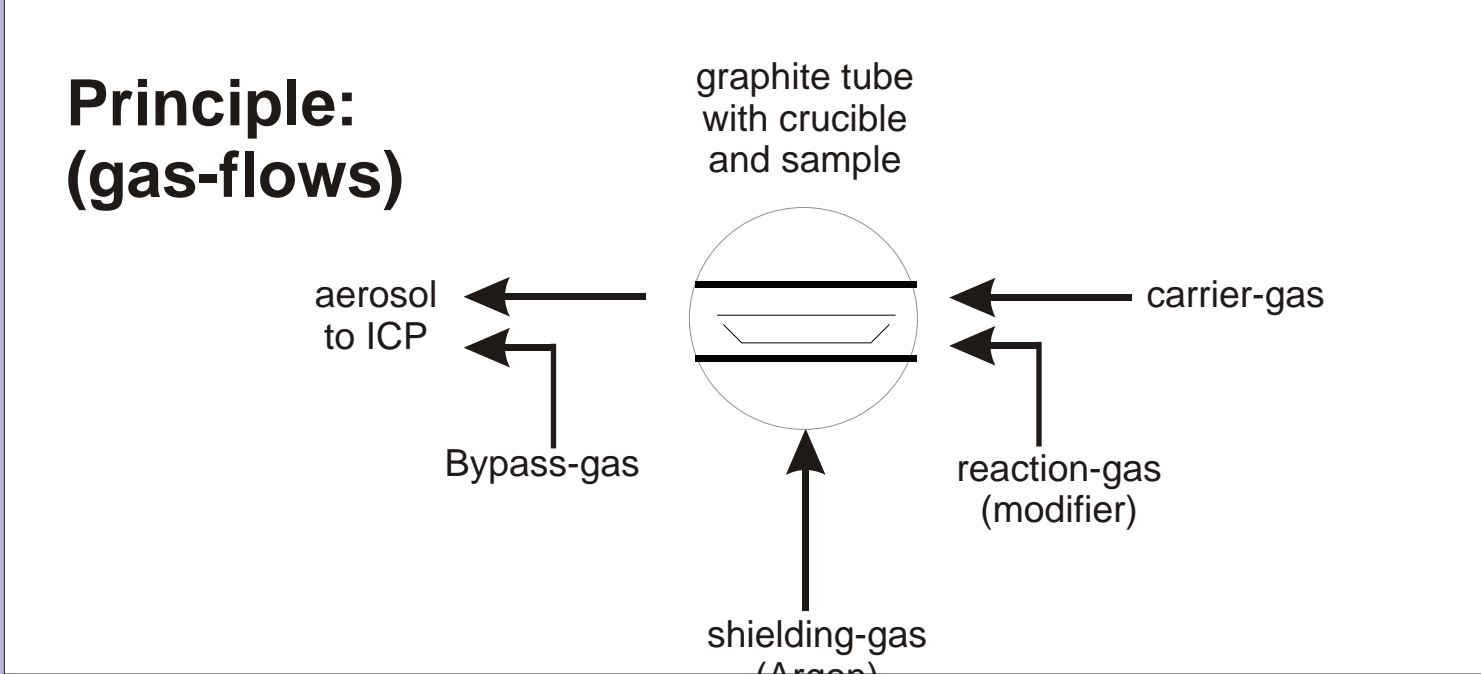
Temperature-controlled evaporation of sample in a graphite crucible positioned in a graphite-tube furnace with Argon atmosphere (up to 3000°C). Electronic controlled addition of a small amount of reaction-gas (modifier).

Transport of the aerosol to the ICP-plasma by optimised gas guide with high transport-efficiency. Integrated microprocessor-control with graphic LCD-display, electronic gas-flow-control and -mixing, synchronisation by electronic interface. This allows the application of individuel time-temperature-programs.

Automatic boat-temperature control by integrated online pyrometer from 10°C up to 3000°C.

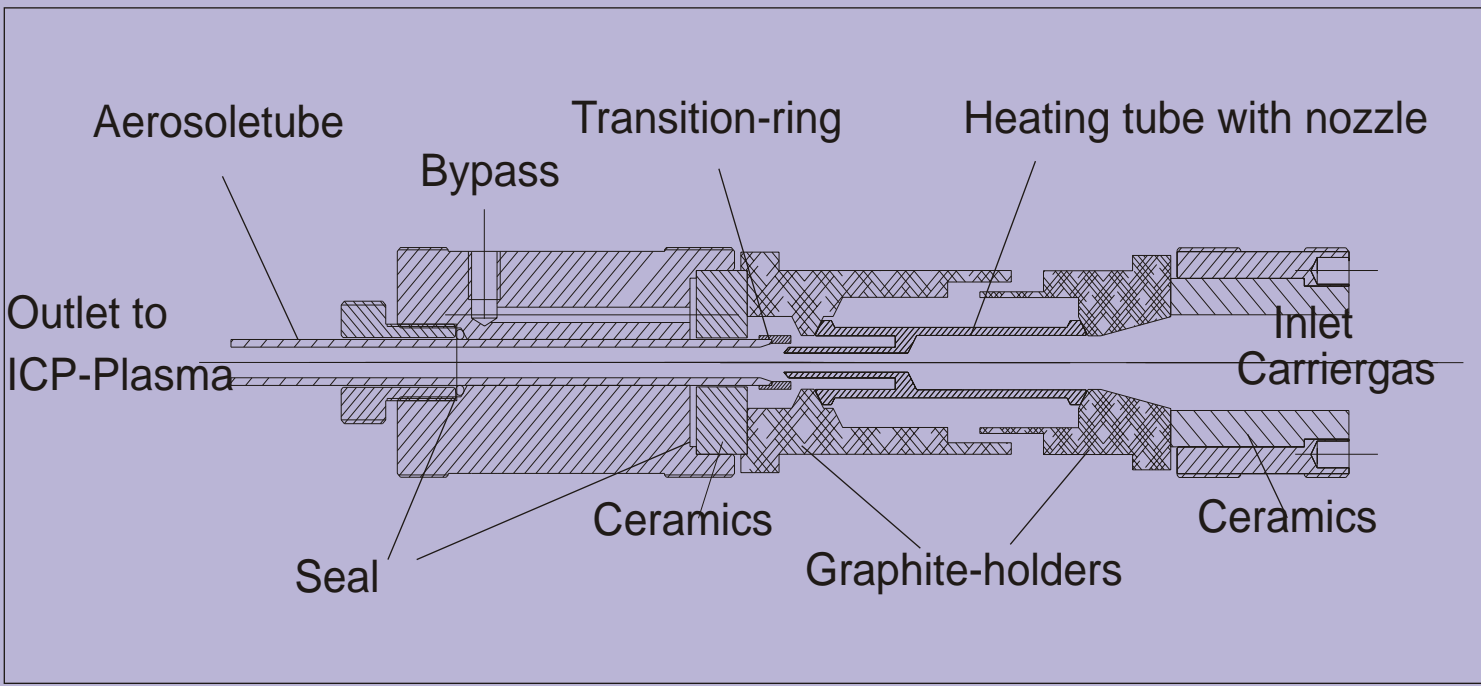
Automated sample-handling by autosampler with up to 50 positions, microbalance.

Schematic of the gas-flow of ETV

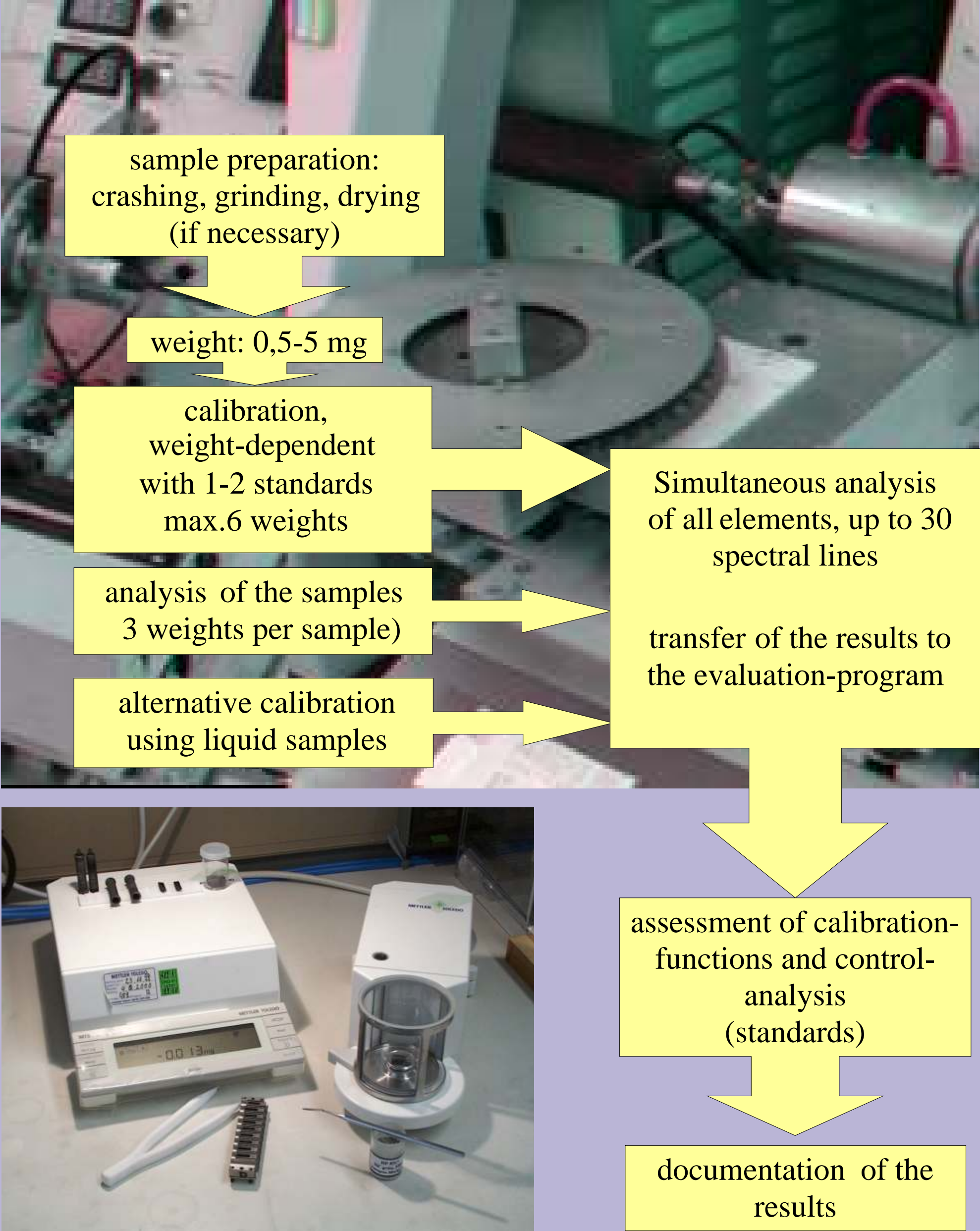


Graphite-furnace, new design

stable up to 3000°C, chemical inert materials, easy handling and maintenance,minimised seals, reduced number of working parts



ETV-analysis: example for a typical procedure



Examples of application

The results of analysed element-concentrations were calculated basing on the shown calibration functions. The points on these common calibration functions (dried liquid standards and solid sample material) show an excellent correlation and thereby prove the correctness and the convincing features of this method.

The investigated materials were:

- Graphite (home standards) ©
- NIST SRM 1515 Apple Leaves (AL)
- Ceramic Materials (BN, TiO₂, TiB₂)
- Milk Powder (MP)

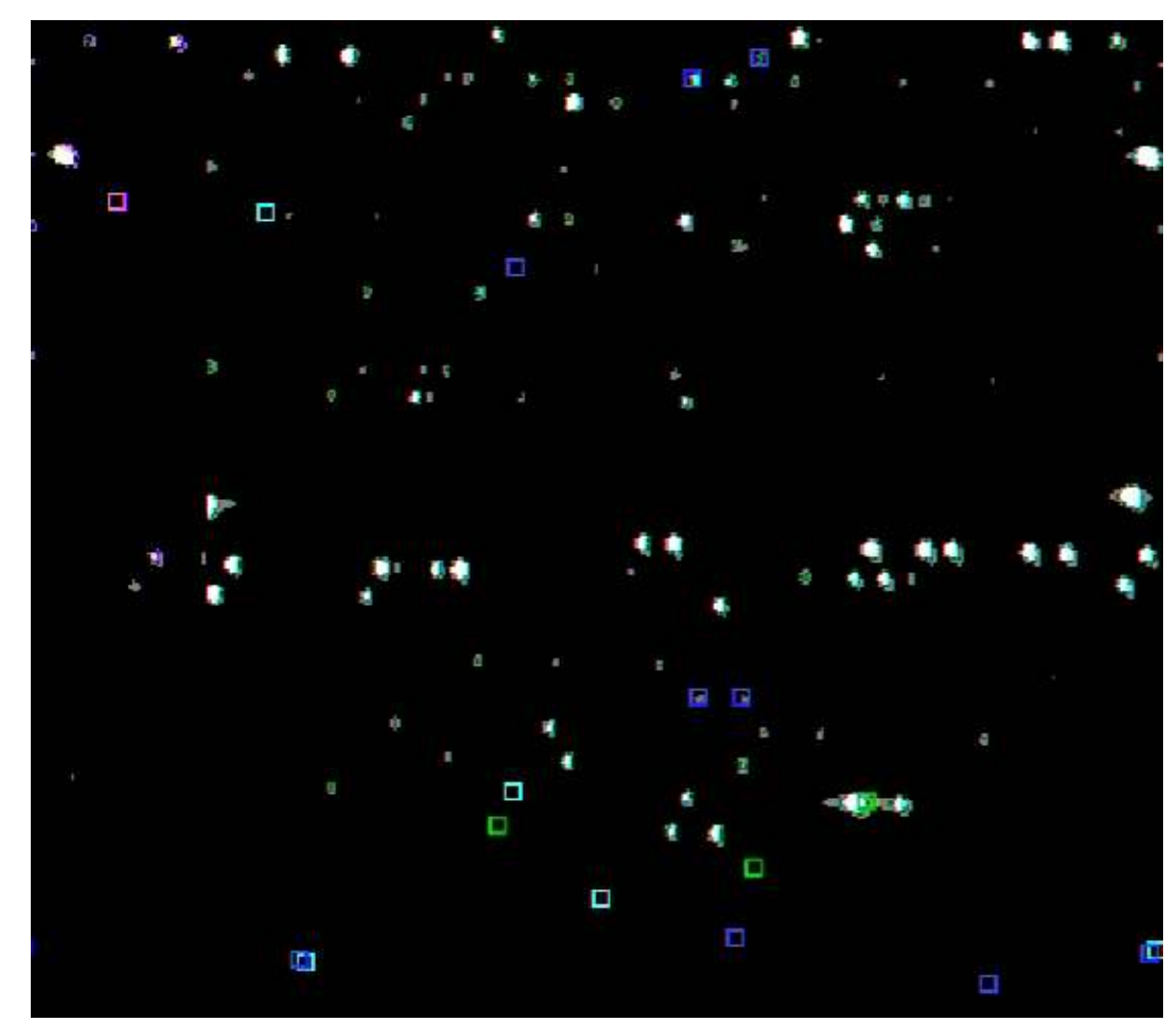
Example:

Gas flow and furnace-program for Iodine

Weight: 1 – 5 mg

Furnace-program: step 1: 30s 300°C
step 2: 2s 300°C to 1600°C
step 3: 28s 1600°C
step 4: cooling 50s
Gases: Argon: carrier 120 ml/min
by-pass 380 ml/min
Freon: 2.3 ml/min

Echelle-picture of the chip area of interest (I,S,P) between the 189th and 156th order



Analytical Lines of I,P,S

Iodine	178.276 (188)	75
	179.903 (186)	5
	183.038 (182)	15
	206.190 (162)	3
Phosphorus	177.499 (189)	100
	178.287 (188)	110
	178.768 (187)	60
	185.891 (180)	40
	185.943 (180)	65
	203.349 (165)	10
	213.618 (157)	90
	214.914 (156)	50
Sulphur	180.731 (185)	220
	182.034 (183)	140
	182.624 (183)	50

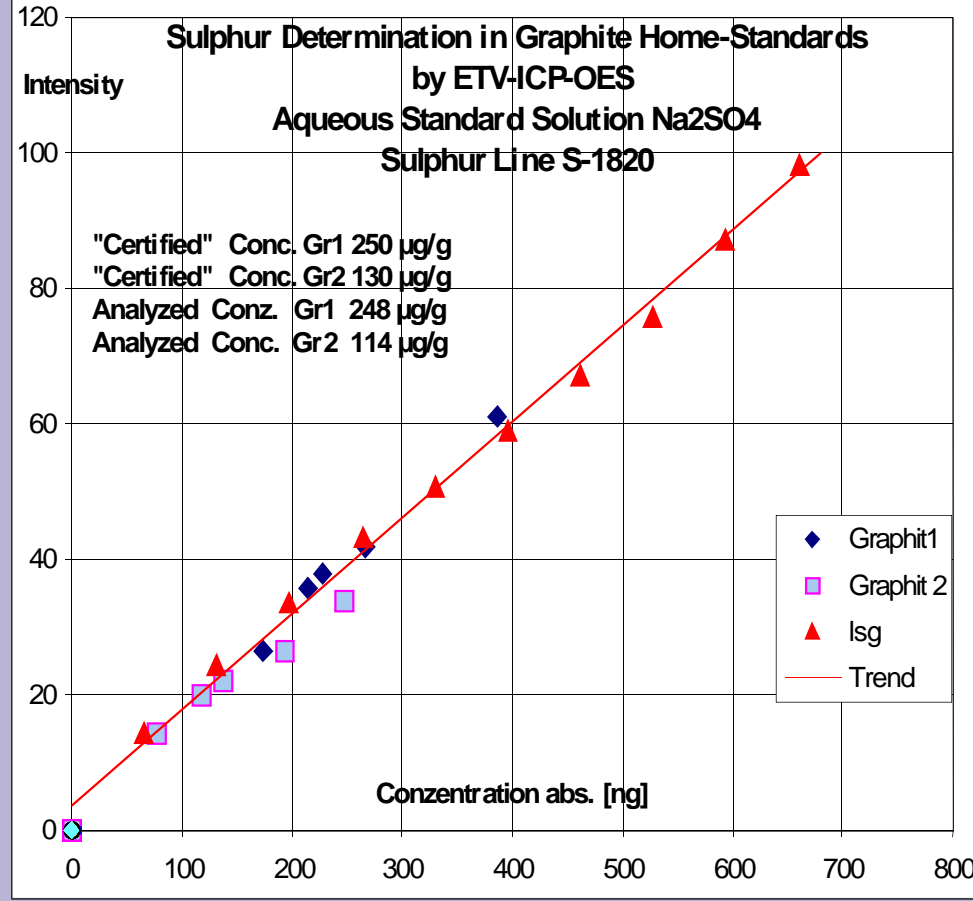
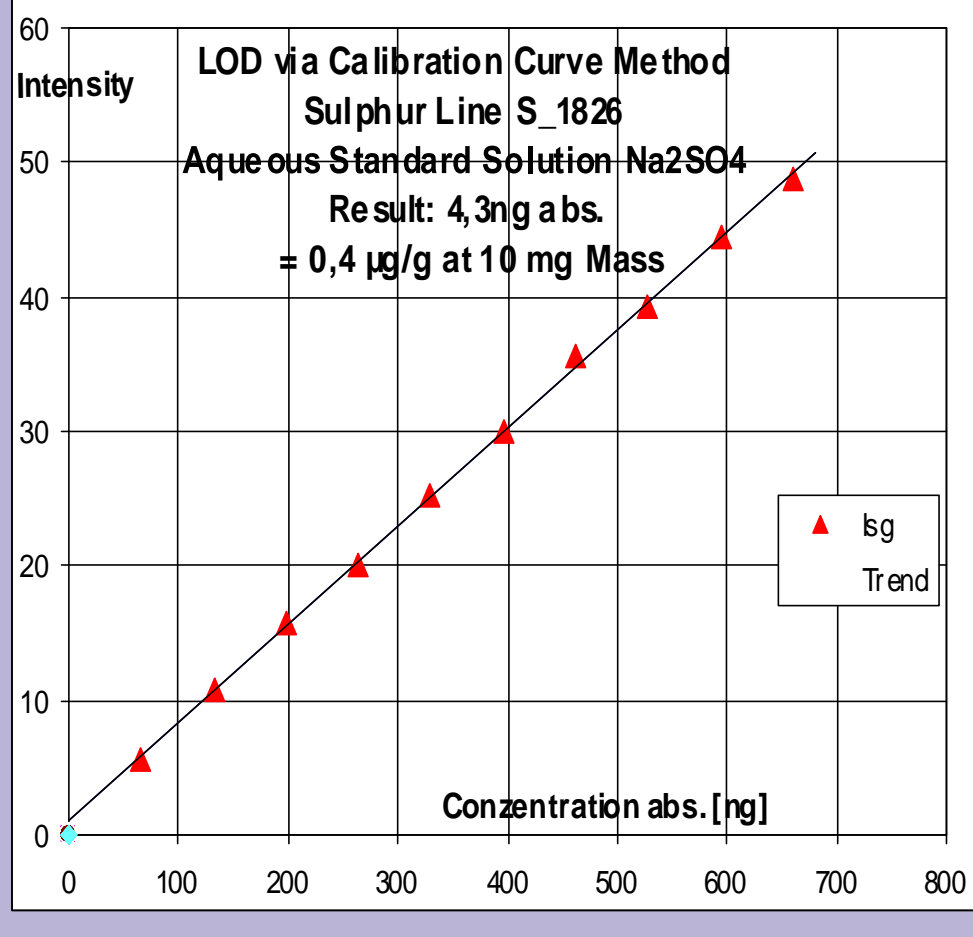
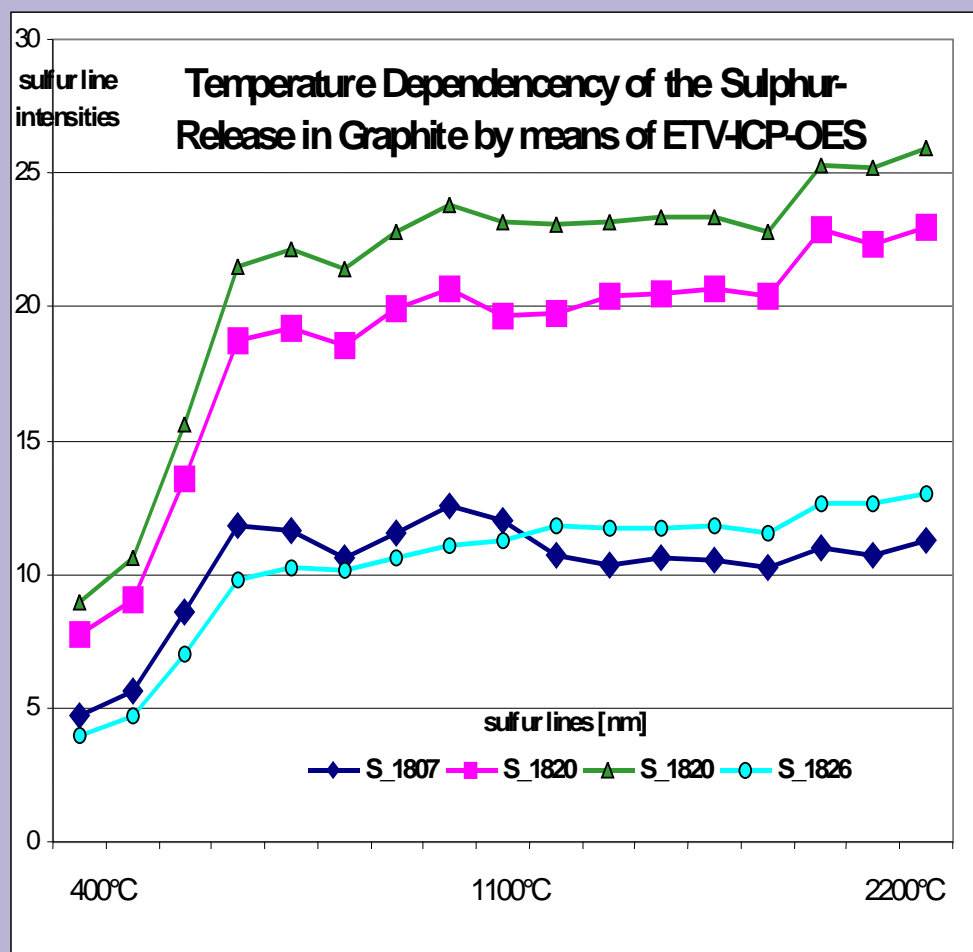
Tab. Experimental setup for ETV-ICP-OES:

ICP-Spectrometer	IRIS-AP Thermo Jarrell Ash Echelle-polychromator, Argon rinsed Echelle grating 60 grooves/mm
Spectral data	Focal distance: 381mm Resolution: at 200 nm width of one pixle 0,0035 nm Spektral range: 175-1050nm
Signal detection	CID-camera Active surface of CID chip:14,3x14,3mm (512 x 512 pixle)
ICP	axially plasma; RF generator: 1150 W at 27,12 Mhz
ETV-unit	ETV 4000 P.Perzl; Spectral Systems; Power supply: max power 400 A; end-on stream system; Furnace control: inside temperature controlled

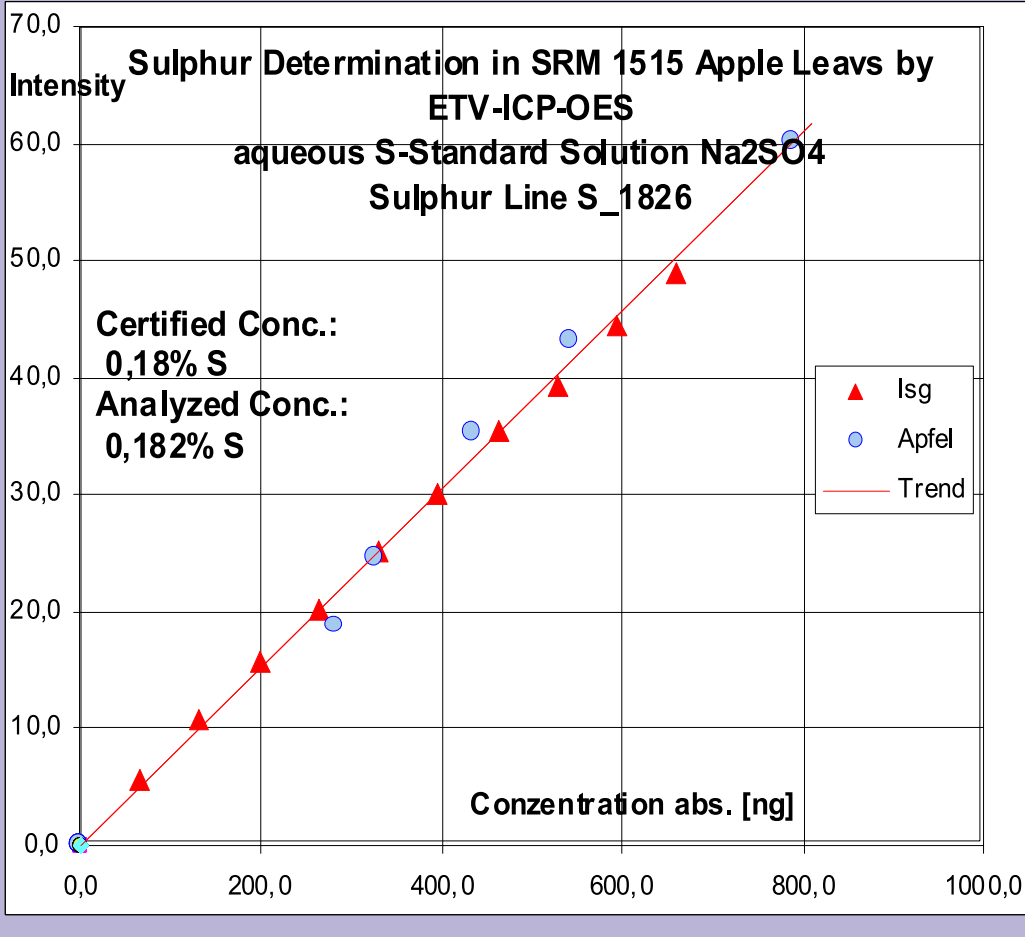
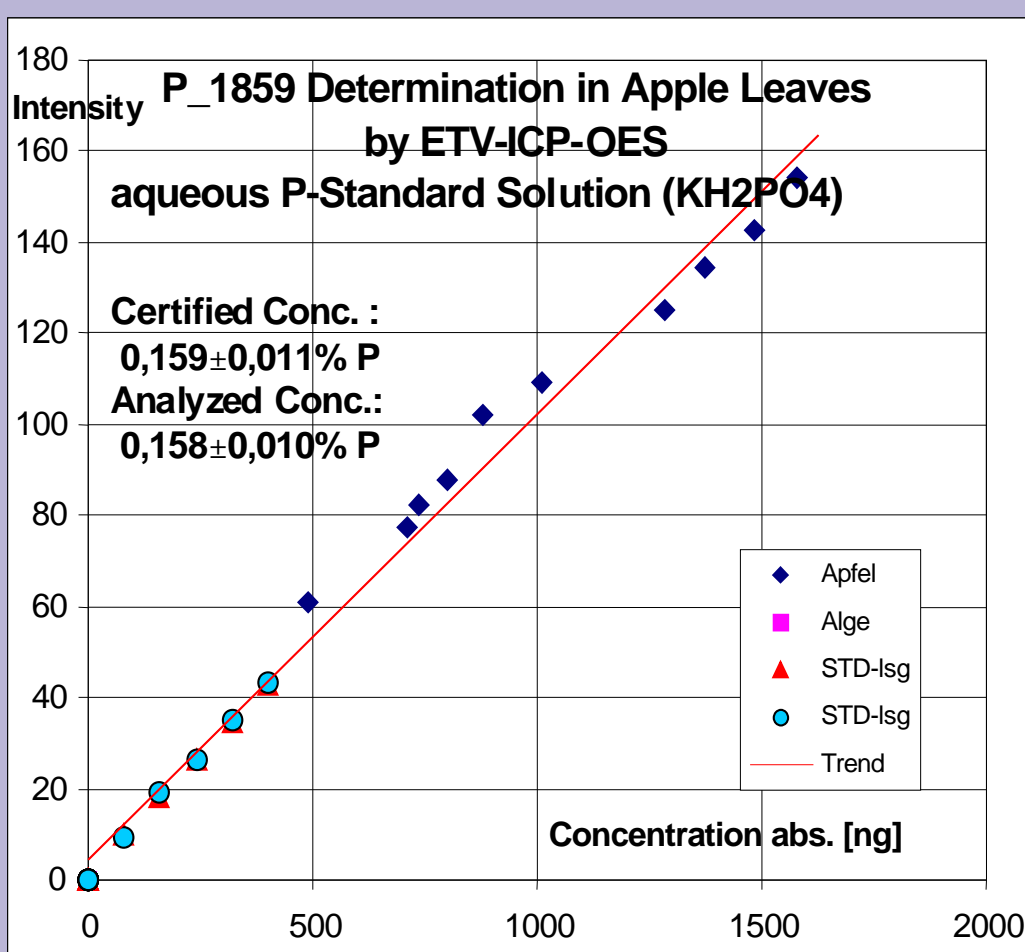
Results

Element	Line	LOD [ng abs.]	Material	Element	concentration	
					expectet	found
I	183.0	3 – 5	TiB ₂	P	20 ± 5	9.5 ± 2
	179.9	7 – 11		P	510 ± 35	620 ± 40
P	185.891	0.7	BN	P	600 ± 50	550 ± 80
	185.943	0.8	Apple leaves	P	1590 ± 110	1580 ± 100
	213.618	0.5		S	1800 ± 100	1820 ± 50
	214.914	0.7	Graphite Gr1	S	250 ± 15	248 ± 10
S	182.0	1 - 2	Graphite Gr2	S	130 ± 15	114 ± 10
	182.6	4 - 5	MP	I	0.8-1.5	1.12 ± 0.25
			MP (standard addition)	I	0.8-1.05	0.95 ± 0.25

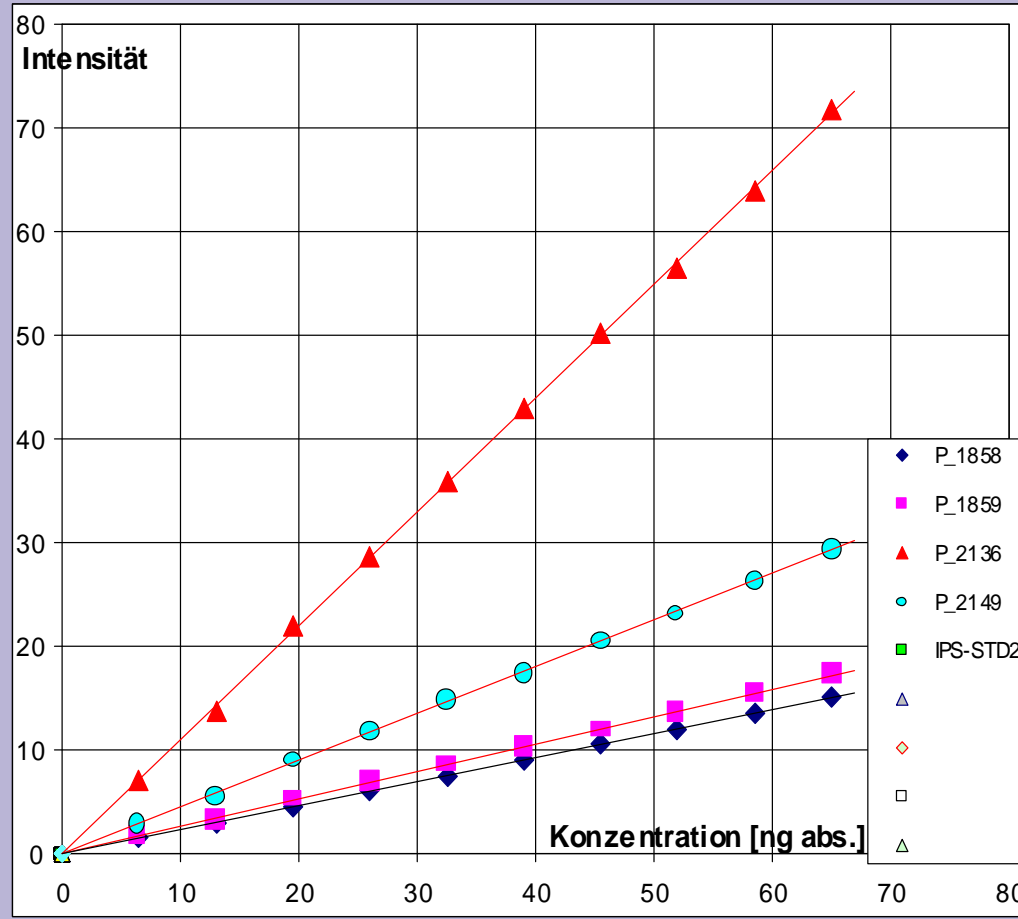
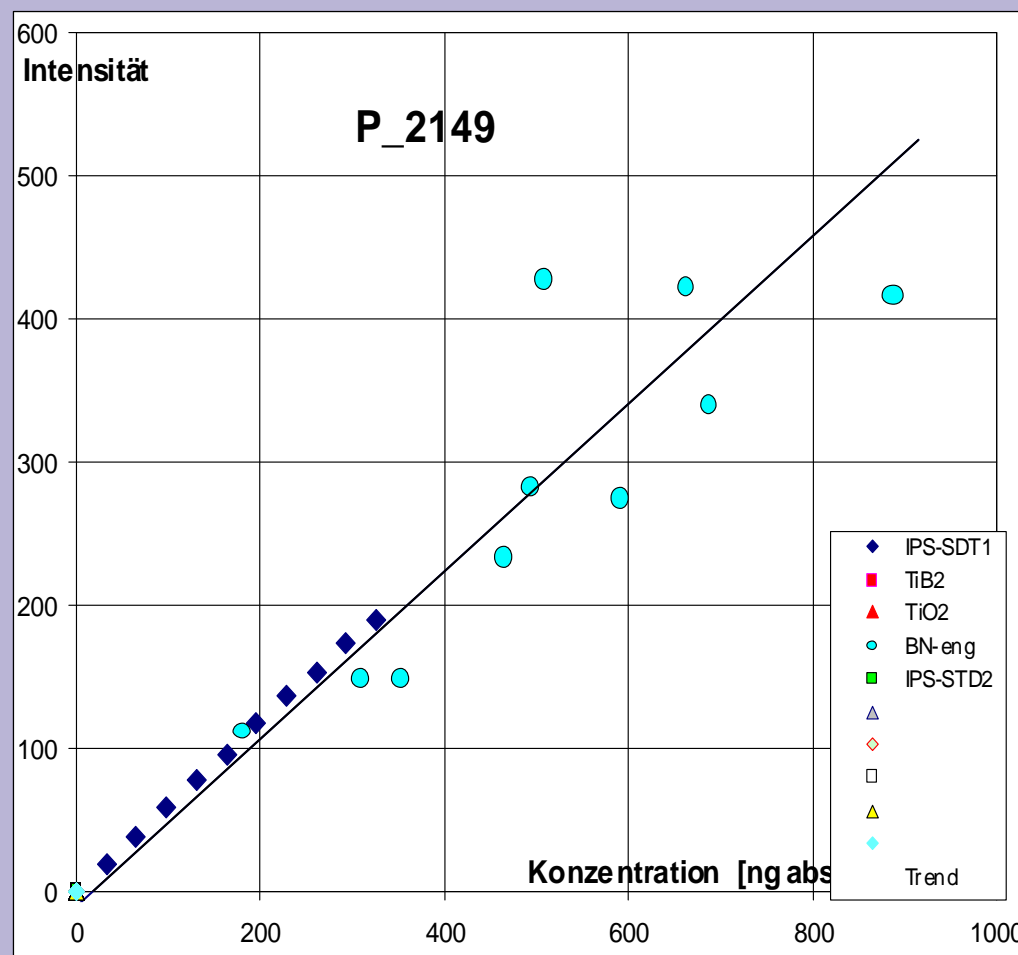
S in Graphite



S, P in Apple Leaves



P in Ceramic Materials



I in Ashed Milk Powder

